

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Not for submission under 37 CFR 1.99)	Application Number		10715628
	Filing Date		2003-11-17
	First Named Inventor	Garol J. Derderian	
	Art Unit	1792	
	Examiner Name	Zervigon, Rudy	
	Attorney Docket Number	MI22-2427	

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20	6344151	B1	2002-02-05	Chen et al.	
21	6638880	B2	2003-10-28	Yamamuka et al.	
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